

MACROPOROUS SILICON DEEP UV FILTERS

V. Kochergin¹, O. Sneh², M. Sanghavi¹, P.R. Swinehart¹

¹Lake Shore Cryotronics, Inc.
Westerville, OH, 43082

www.lakeshore.com

²Sundew Technologies, LLC,
1619 Garnet St., Broomfield, CO 80020

www.sundewtech.com

LakeShore.

Outline

- Introduction and Rationale
- Physical basis of filtering in Macroporous silicon membranes
- Macroporous Silicon chemistry and fabrication
- Brief process flow diagram
- ALD coating description
- Experimental results
- Conclusions
- IR and other applications

Existing technology

ABSORPTION-BASED

- **Not suitable for deep UV range**
- **Available materials absorb across entire deep UV spectrum**

INTERFERENCE-BASED

- **Limited width of the rejection bands;**
- **Poor physical longevity and lack of environmental stability (deep UV filters)**
- **Strong angular dependence of the pass band or rejection edge position**

Transmission mechanism through an uncoated MPSi array

- Up to 700-900nm- transmission through the pore leaky waveguide array
- From 700-900nm to $\sim 5\Lambda$ – transmission through the Si host waveguide array
- 5Λ and above- transmission through an “effective medium”

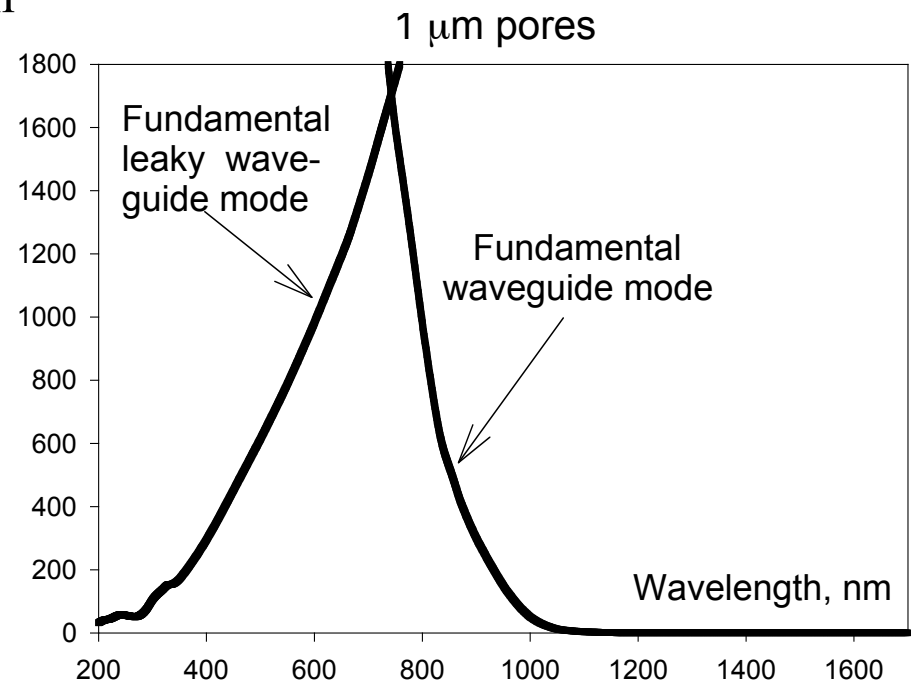
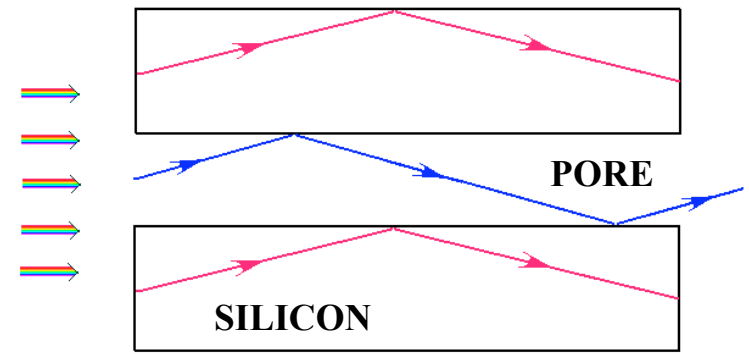
UV-visible range:

$$\alpha = f_0 \lambda^2 / d^3$$

$$\lambda_{-3dB} = \sqrt{\ln(2) \cdot \frac{d^3}{f_0 \cdot L}} \quad \lambda_{-20dB} = \sqrt{\ln(100) \cdot \frac{d^3}{f_0 \cdot L}}$$

$f_0 \approx 0.09$ index factor

Sharpness and position of the rejection edge are bounded!

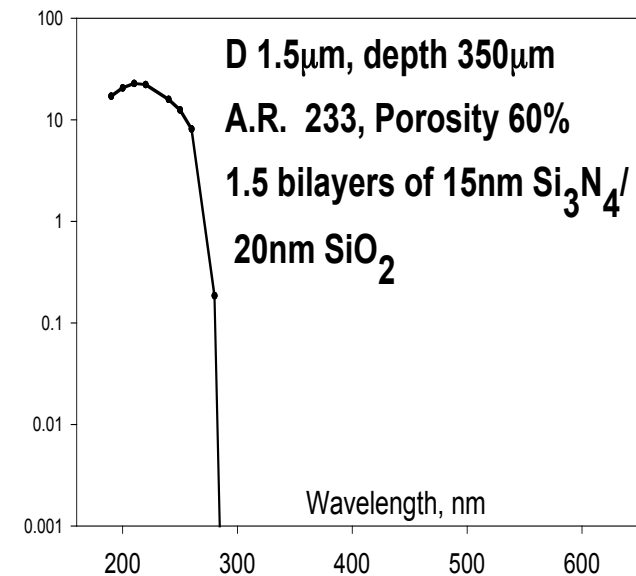
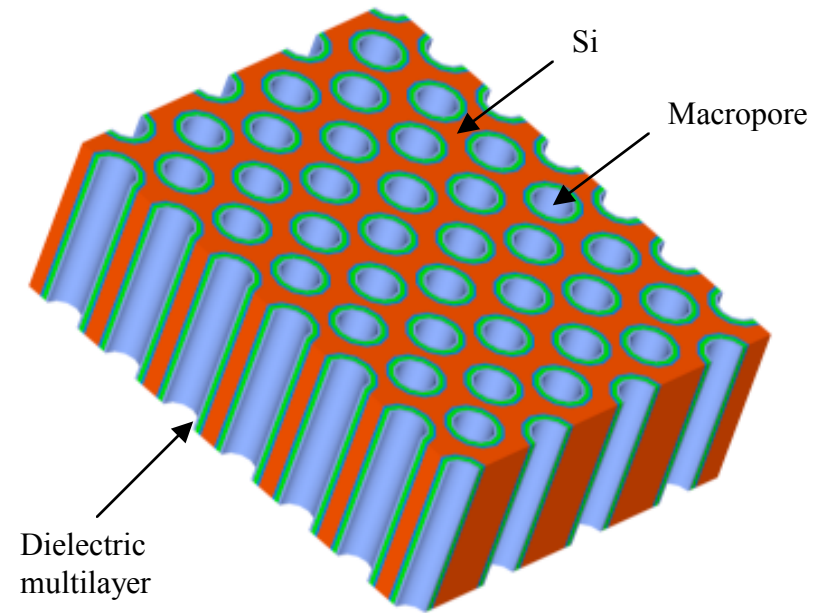


Formulas taken from [I. Avrutsky and V. Kochergin, *Appl. Phys. Lett.*, 82, 3590 (2003)]

LakeShore.

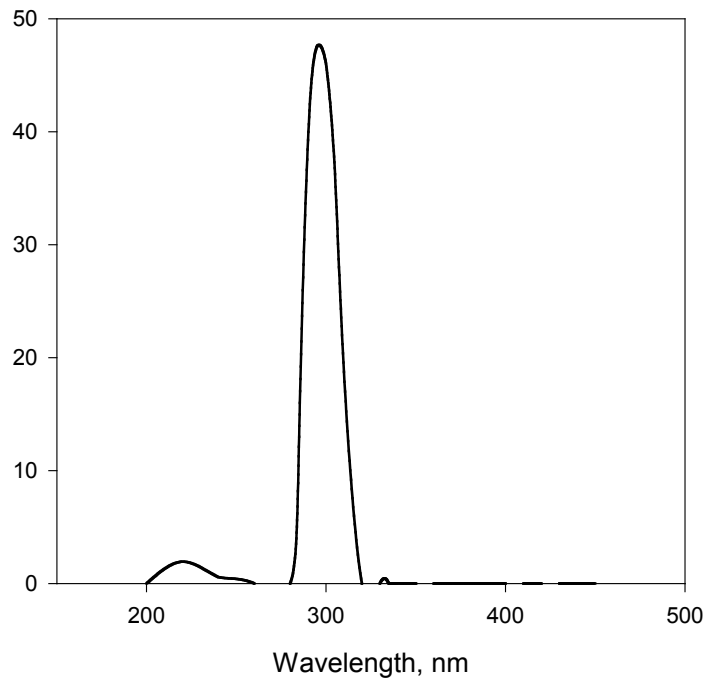
Coated MPSi arrays

- Leaky mode losses can be selectively adjusted.
- High rejection levels are predicted.
- Transmission down to far and extreme UV is possible.
- Spectral position and shape of pass- and rejection bands are independent on angle of incidence.
- Far fewer layers are necessary in order to achieve a comparable edge sharpness and rejection level than in common interference filters.
- Filters are much more environmentally and thermally stable.

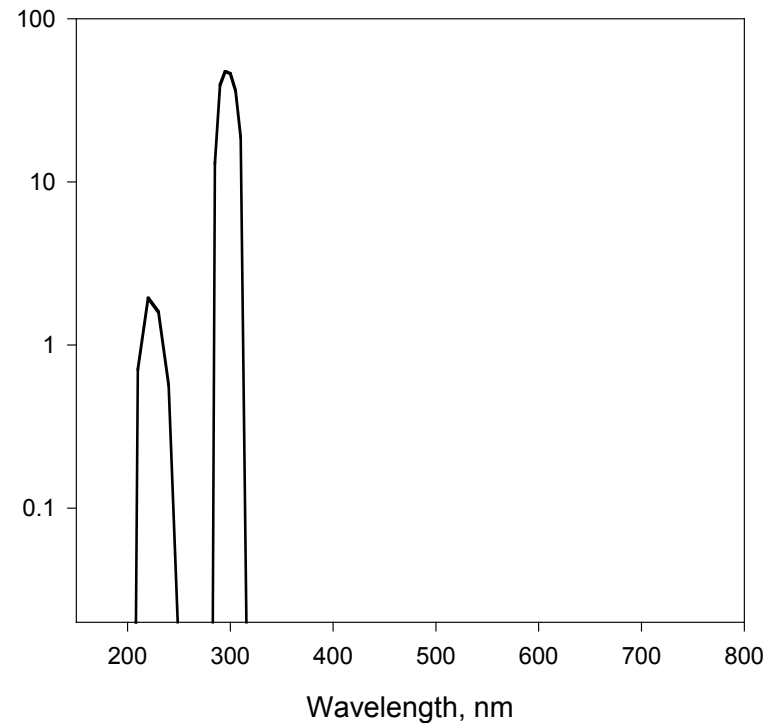


LakeShore.

Design (narrow bandpass filter)



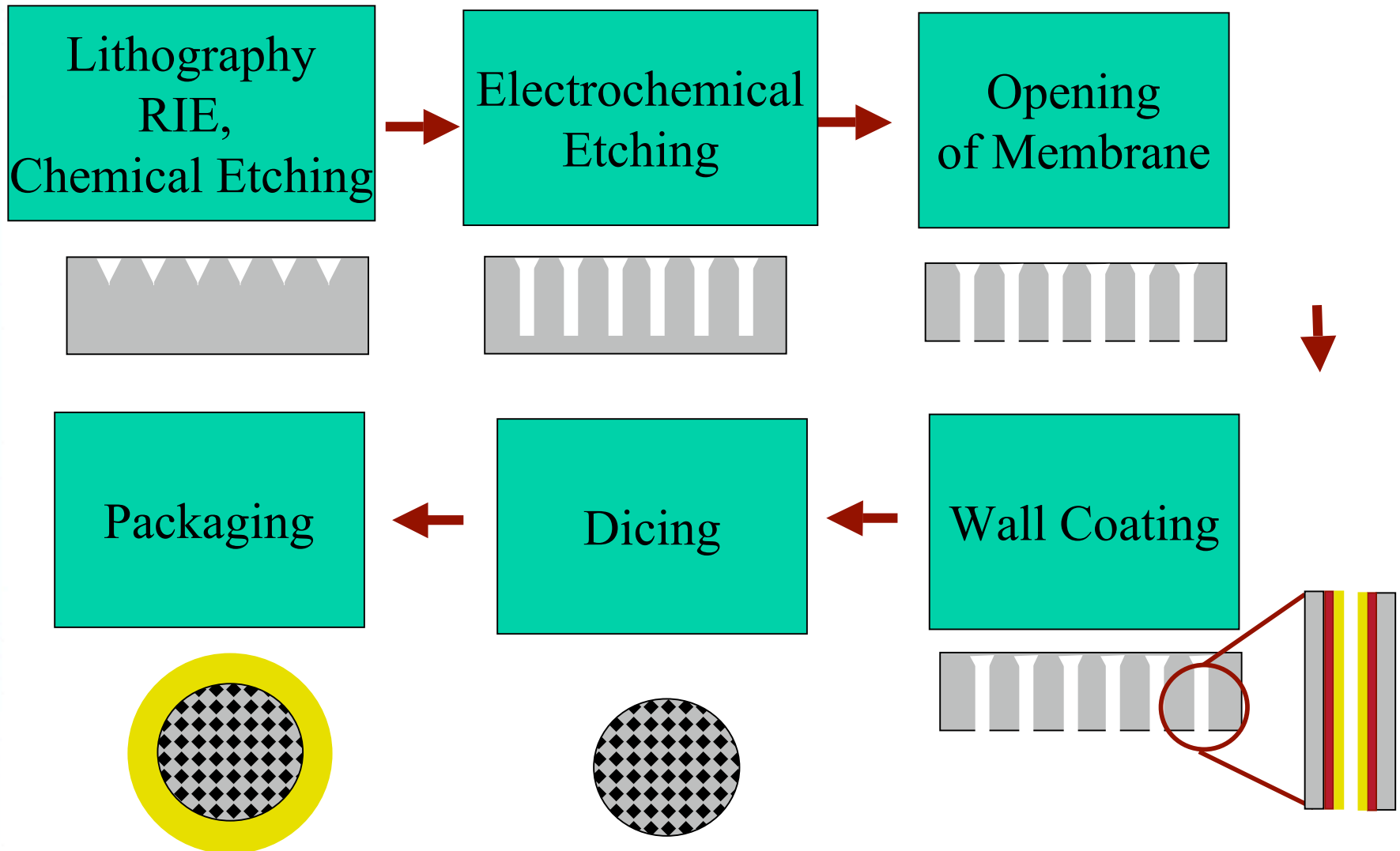
a)



b)

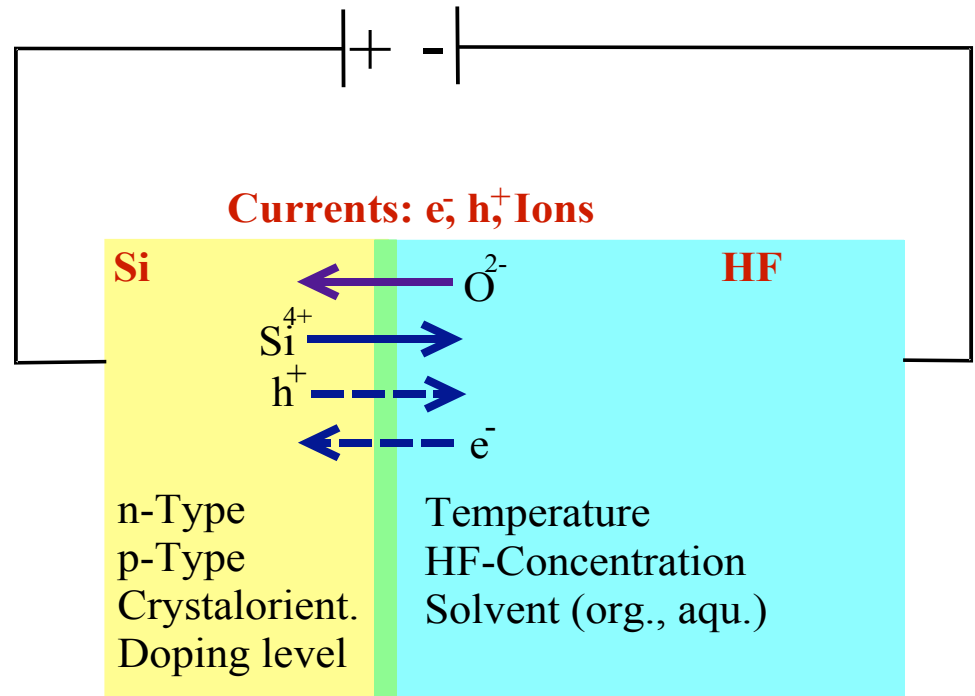
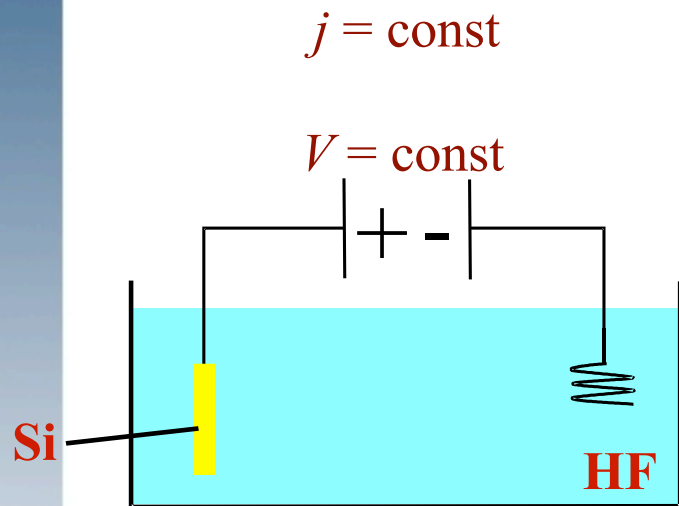
Numerically calculated spectral dependences of the transmission through an MPSi membrane with a 19-layer pore wall coating designed as a narrow bandpass filter, with band centered at 300nm. The transmission in a) is plotted on a linear scale, while in b) is given on a logarithmic scale.

Process flow



LakeShore.

Porous silicon etching



Interface:

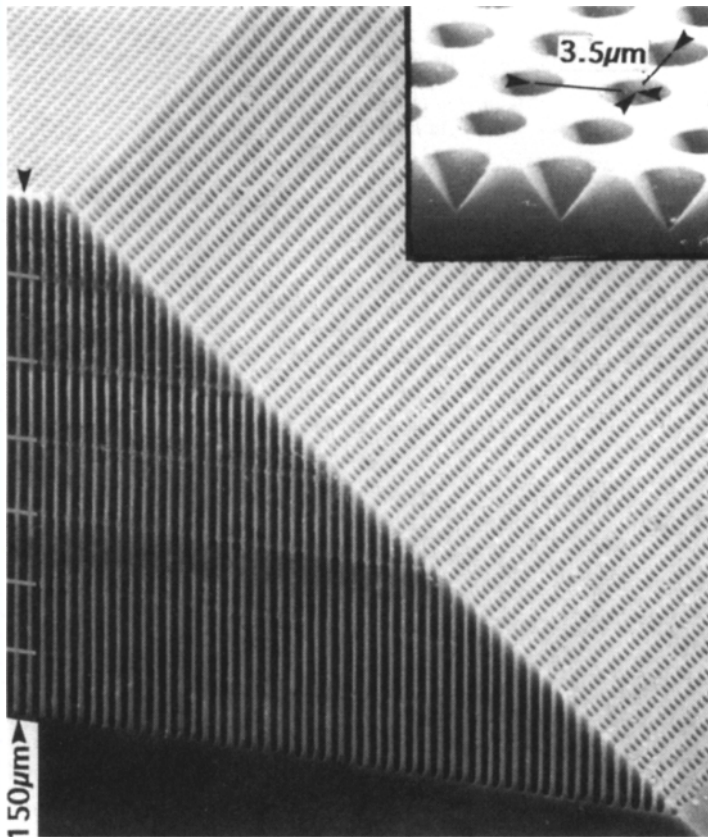
- Porous Silicon
- (Electropolishing can occur)

n-Si: Current limitation by hole supply
Illumination of the silicon is necessary.

LakeShore.

Porous silicon etching (continuation)

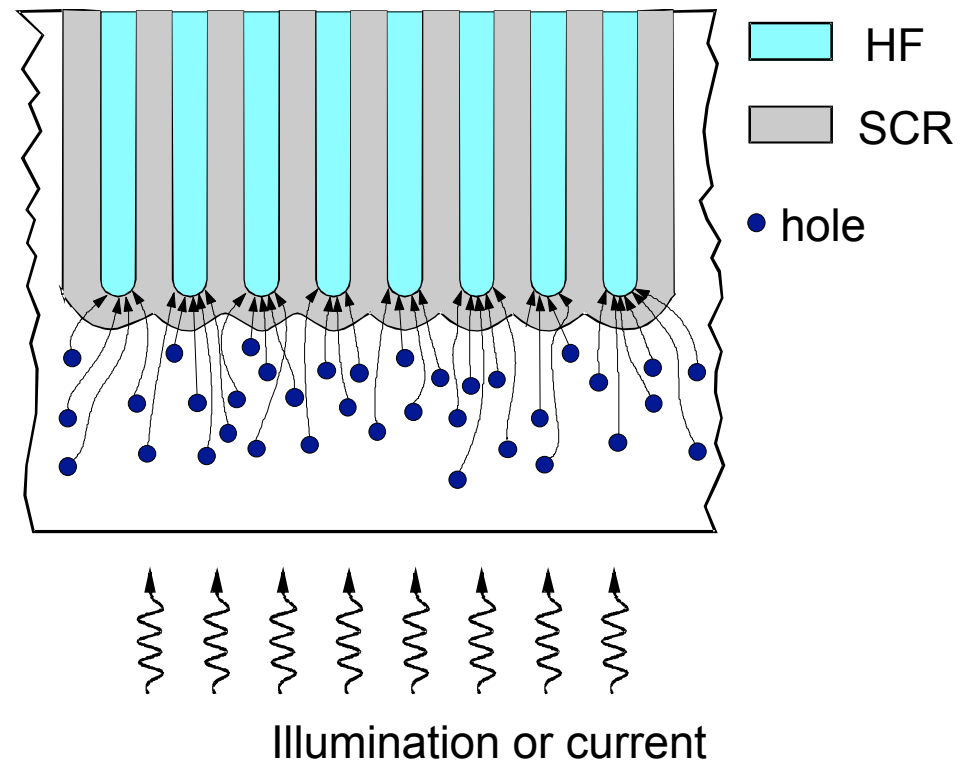
V. Lehmann, H. Föll,
J. Electrochem. Soc., 137, 653 (1990)



V. Lehmann, *J. Electrochem. Soc.*, 140, 2836 (1994)

Macropores in silicon

- space charge region around macropores
- photo (or electrical) generation of holes
- holes are minority carriers

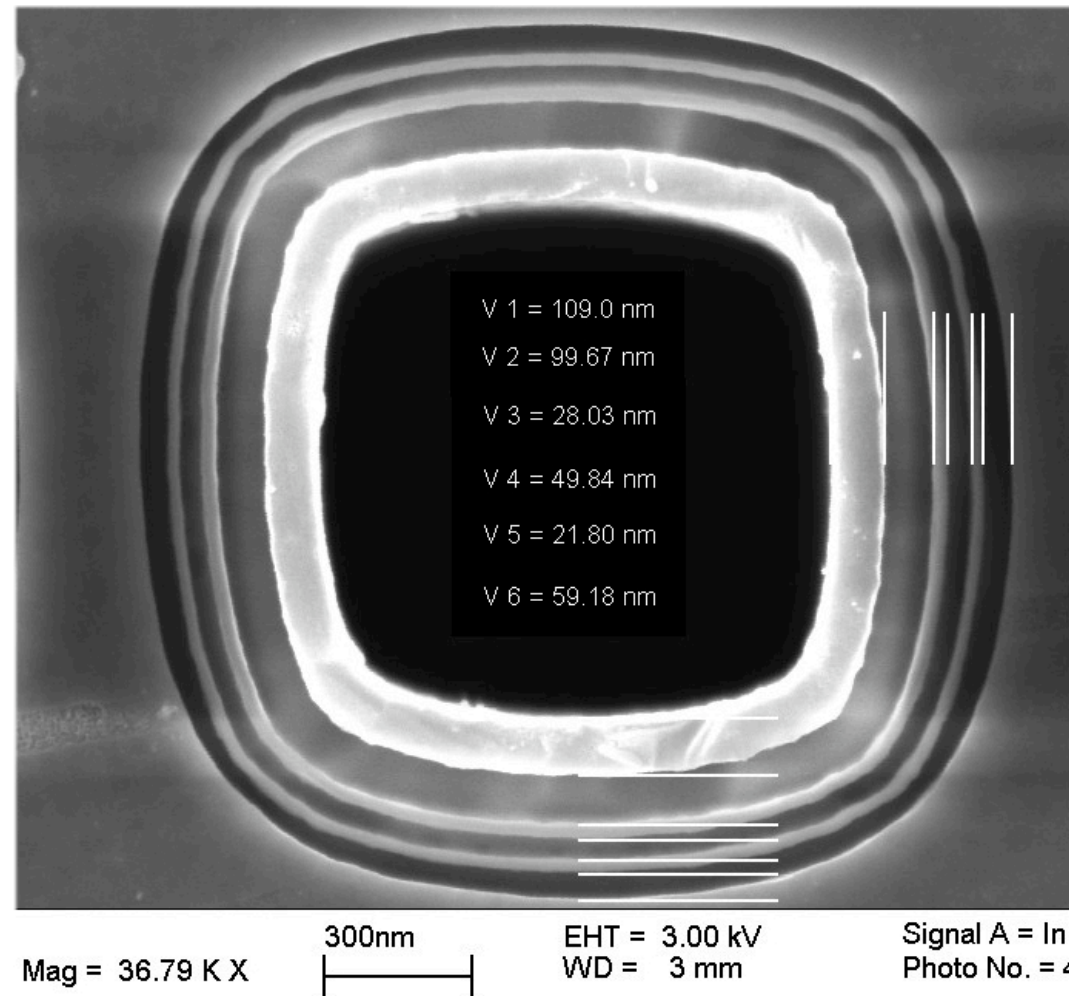


LakeShore.

Multilayer coating of the pore walls (LPCVD)

Coating of MPSi
structure is
demonstrated

- Coating is not uniform
- High stresses
- Very limited choice of materials



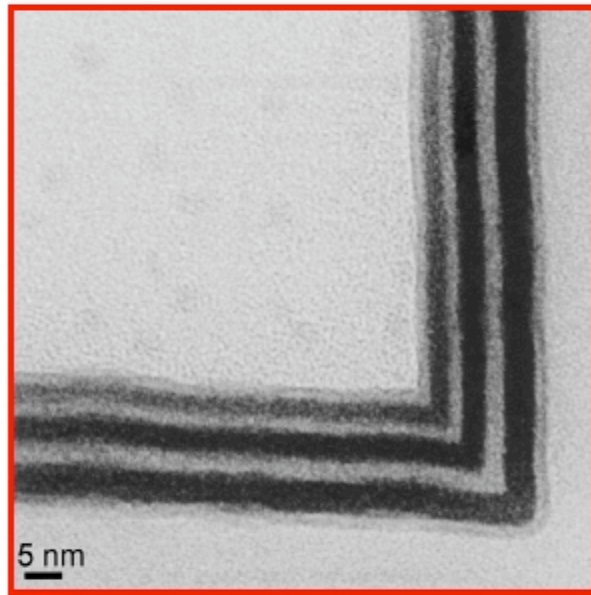
LPCVD pore wall coating and SEM images done by
MEMS PI. www.memspi.com

LakeShore.

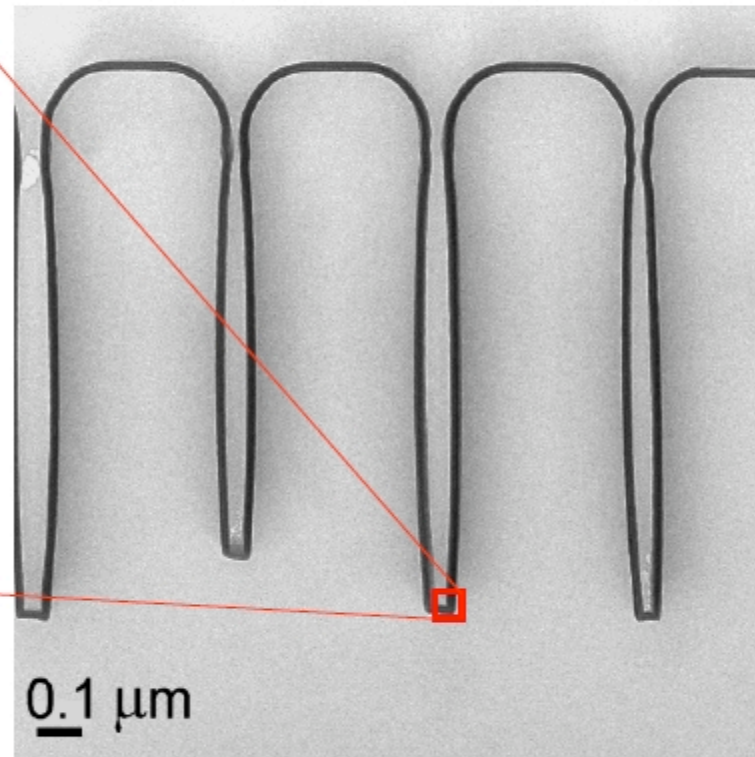
Atomic layer deposition (ALD)

ALD - Atomic Level Precision - 100% Conformal Films

100% Conformal



Nano-Layered Films



Ofer Sneh et al., Thin Solid Films 402 (2002) 248



Sundew Technologies

*Sundew Technologies, LLC - Proprietary
For disclosure to BAE by LakeShore Cryotronics*

3

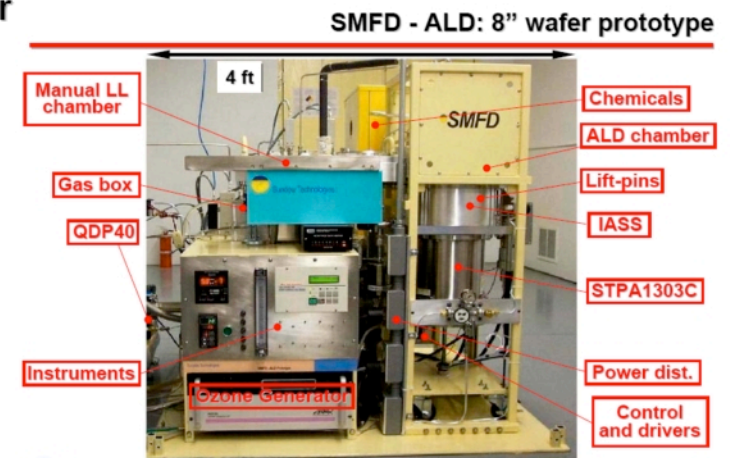
LakeShore.

ALD (continuation)

ALD - Atomic Level Precision - 100% Conformal Films

- ALD is inherently 100% conformal
- The key is the layer-by-layer growth
- Transport time into high aspect ratio structures is fast (~100 msec/mm)
- **The challenge is - chemical delivery.** For example, 8" DRAM wafer (70 nm generation) requires 6×10^{18} precursor molecules per dose !!!
- An Ultra High Area (UHA) substrate such as a porous silicon membrane requires 6×10^{19} precursor molecules per dose !!! \Rightarrow 87 grams of trimethylaluminum per 1 μm of film! (\$50 per technical grade precursor)

Several dozens of different coatings (metals, semiconductor and dielectrics) have been demonstrated

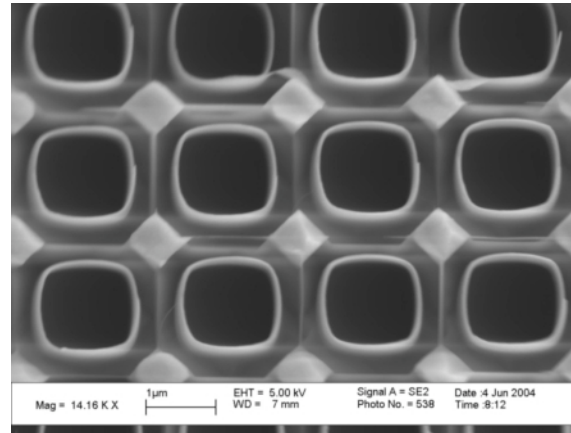
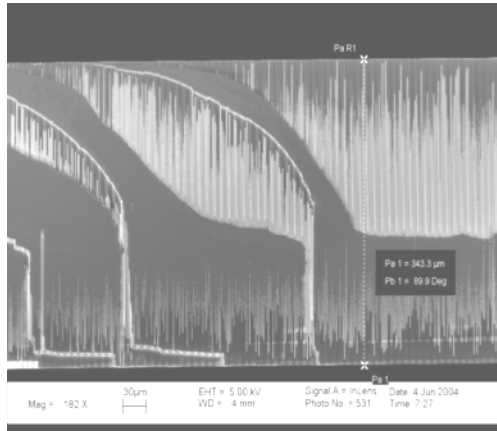


Sundew Technologies

Sundew Technologies, LLC - Proprietary
For disclosure to BAE by LakeShore Cryotronics

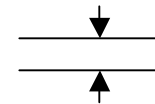
LakeShore

Coating uniformity



Good quality layers (granular structure was not observed)

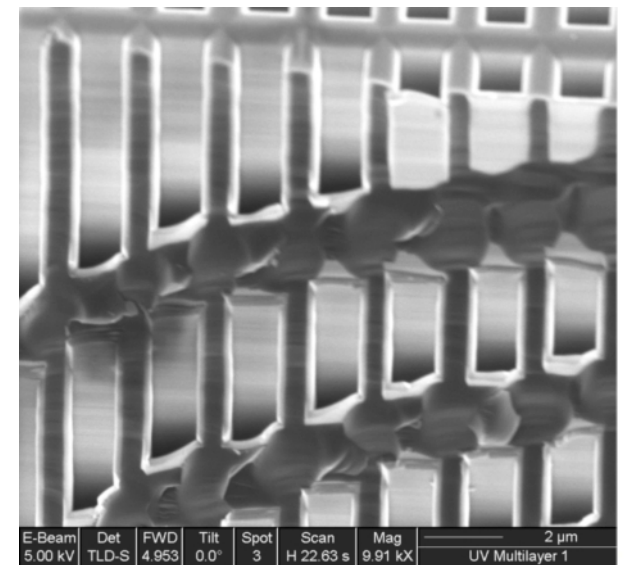
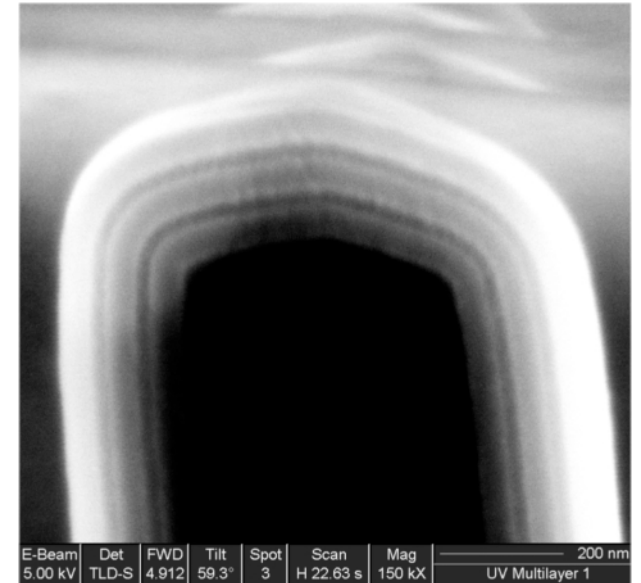
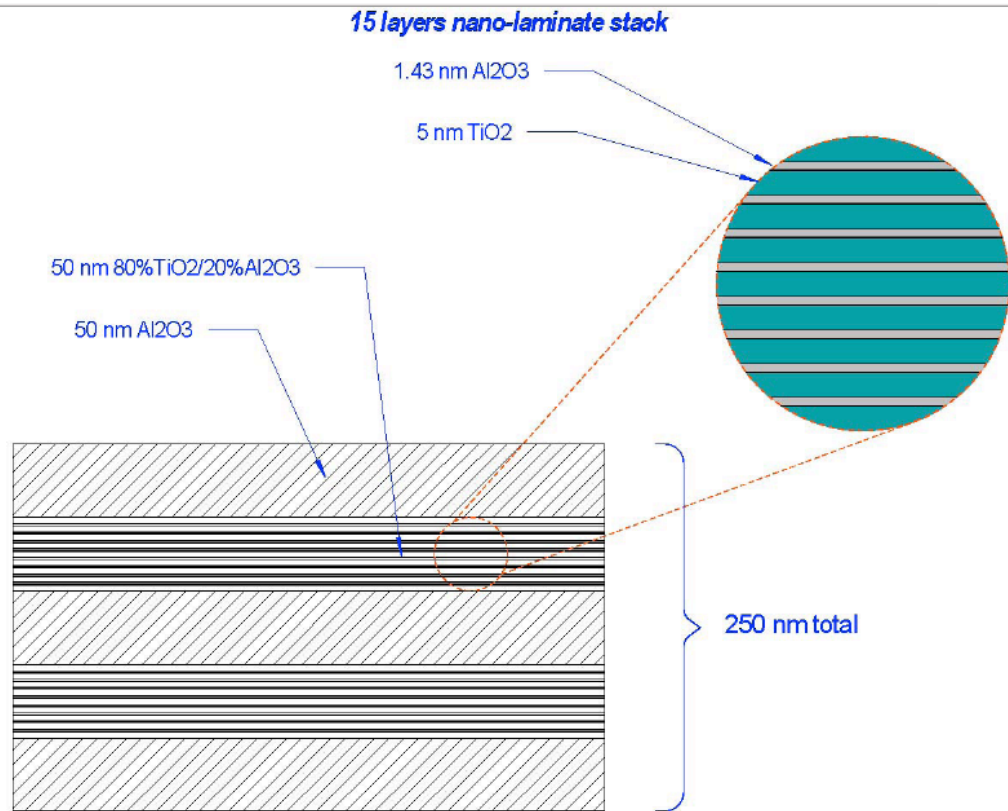
Better than 5% for Al_2O_3



82nm

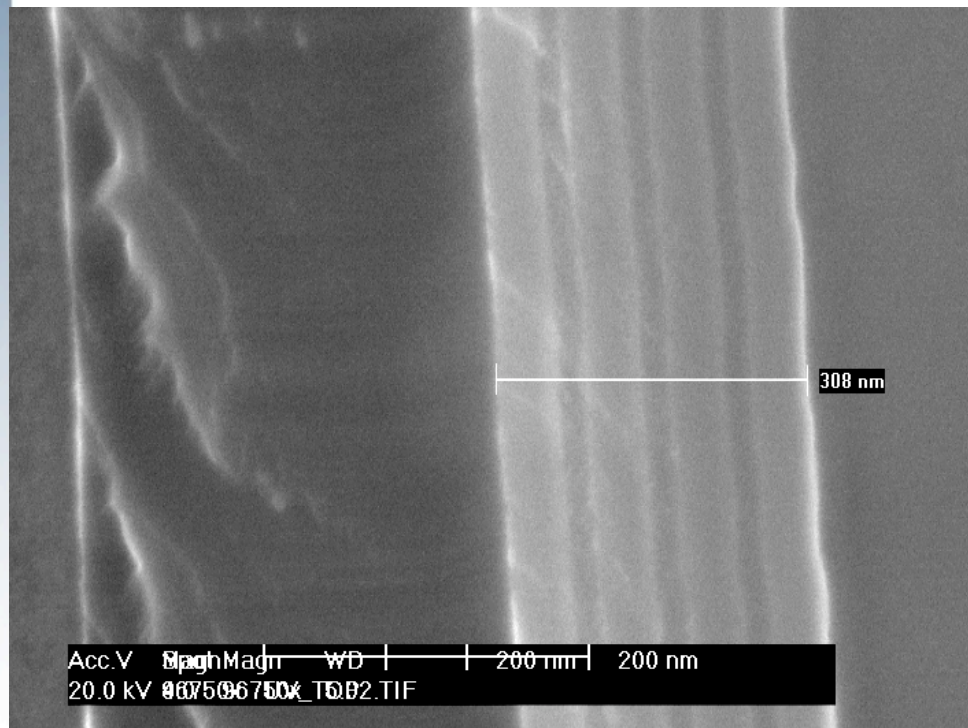
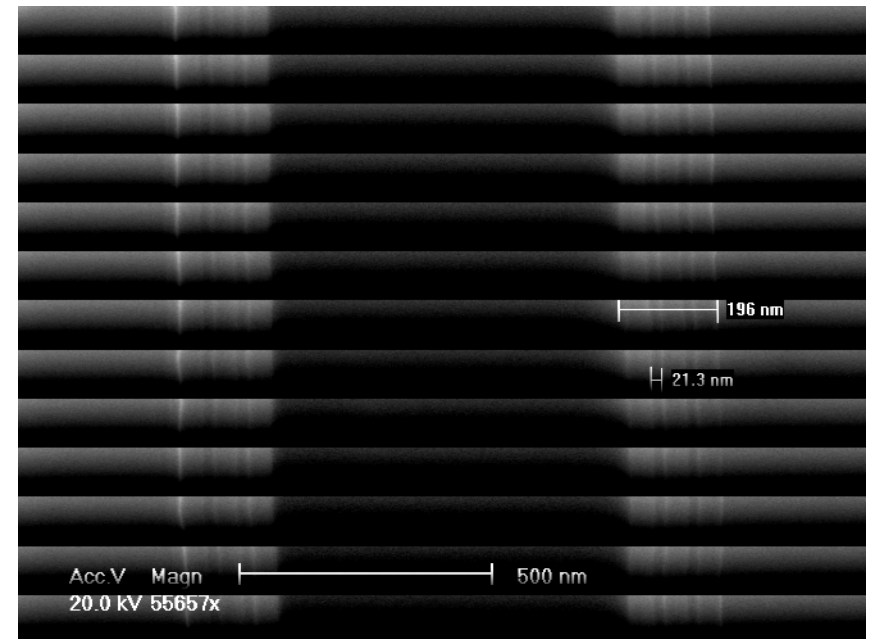
HfO_2 trials were not successful

Nanolaminated stacks and refractive index engineering



LakeShore.

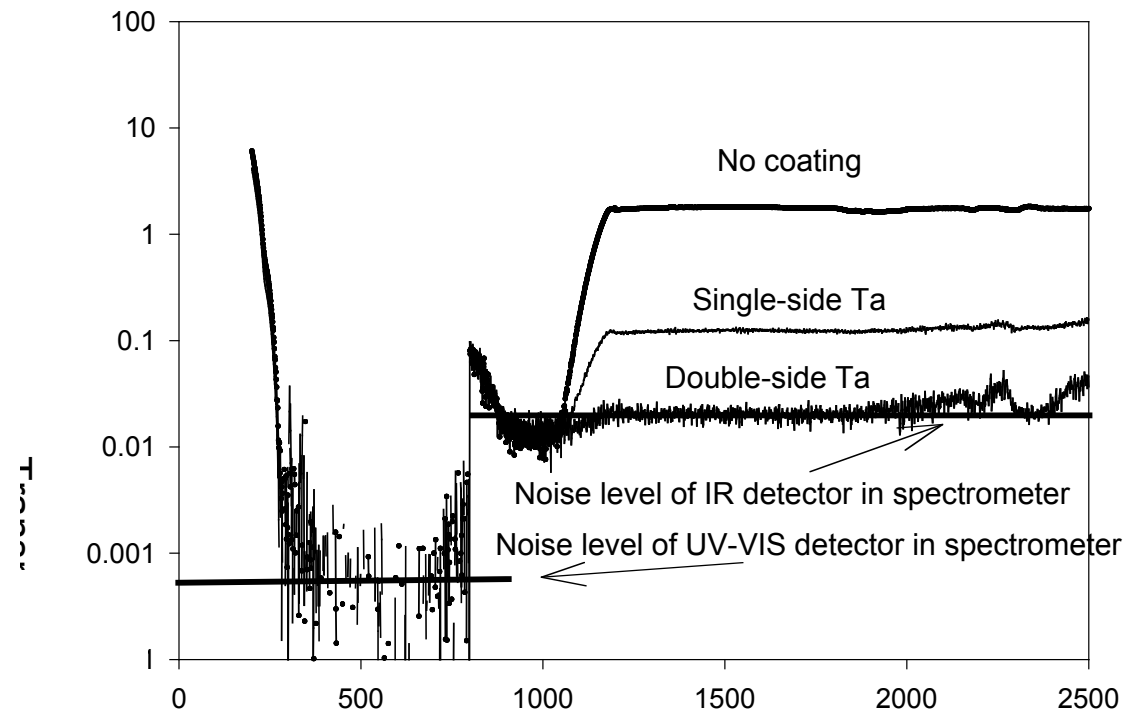
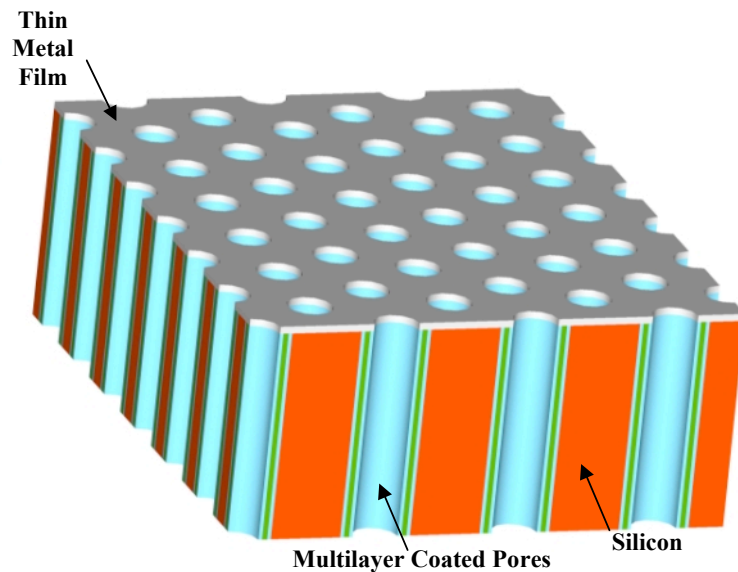
5-layer TiO₂/Al₂O₃ ALD coating (ALD)



7-layer TiO₂/Al₂O₃ ALD coating (ALD)

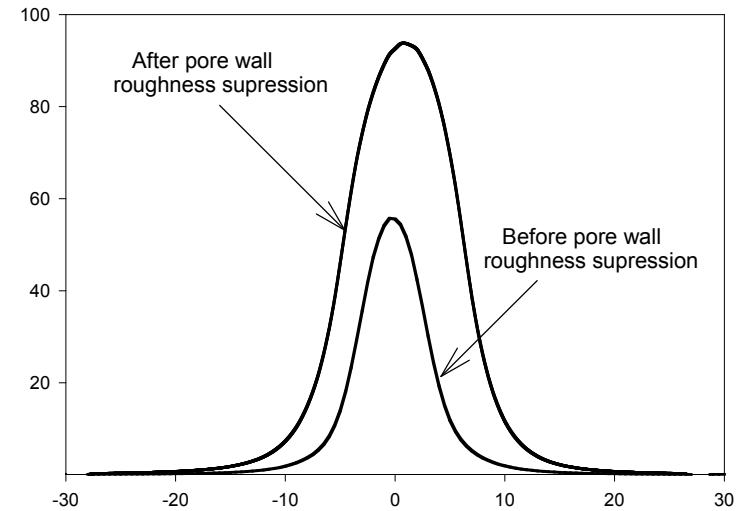
LakeShore.

Wide blocking, higher than 5 OD

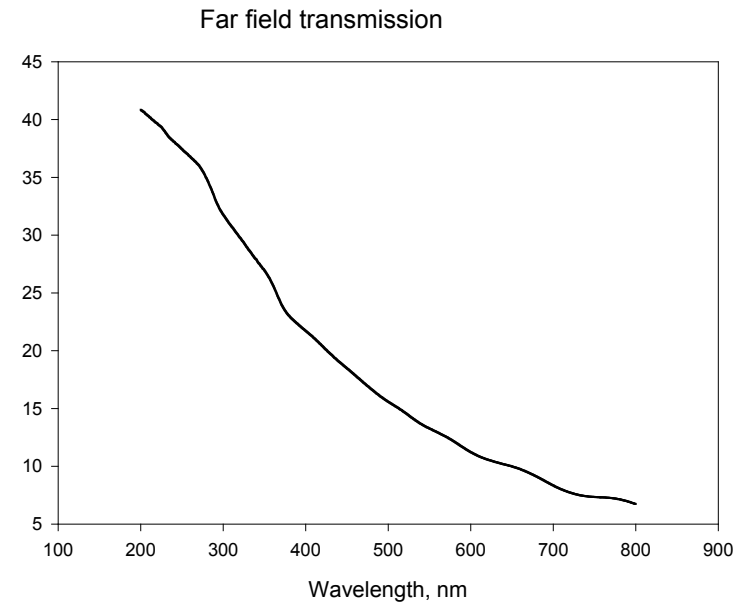
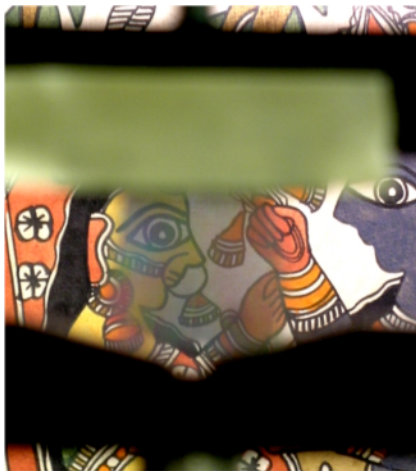


LakeShore.

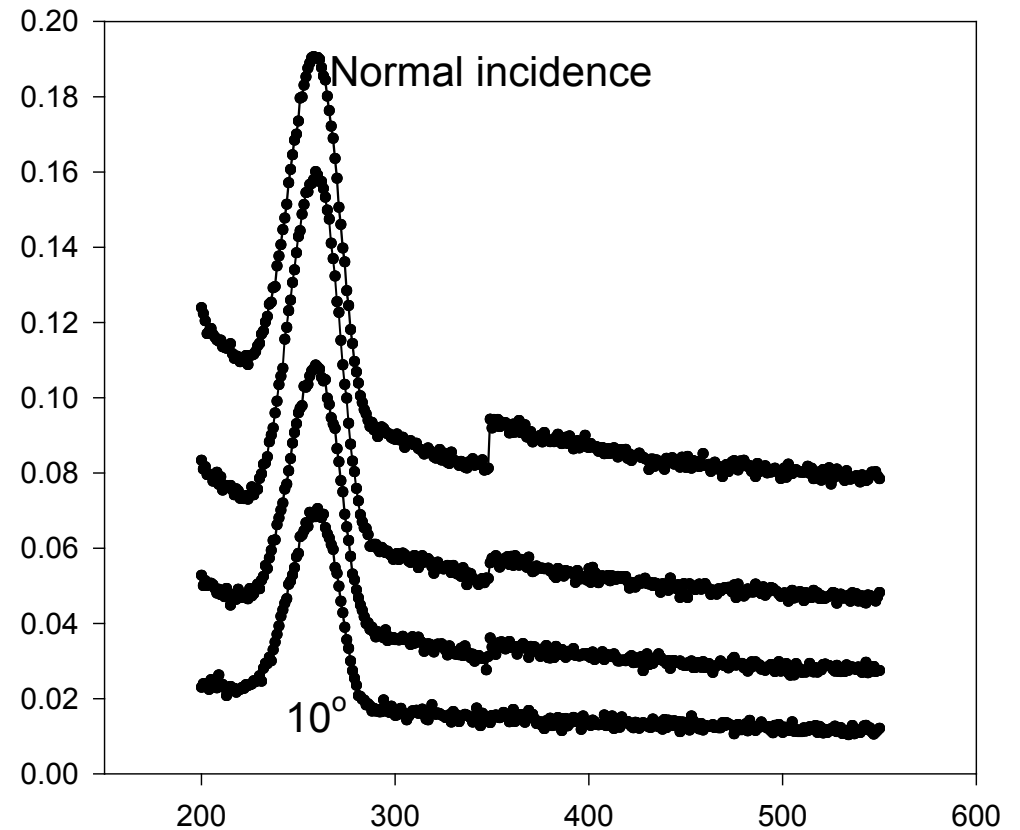
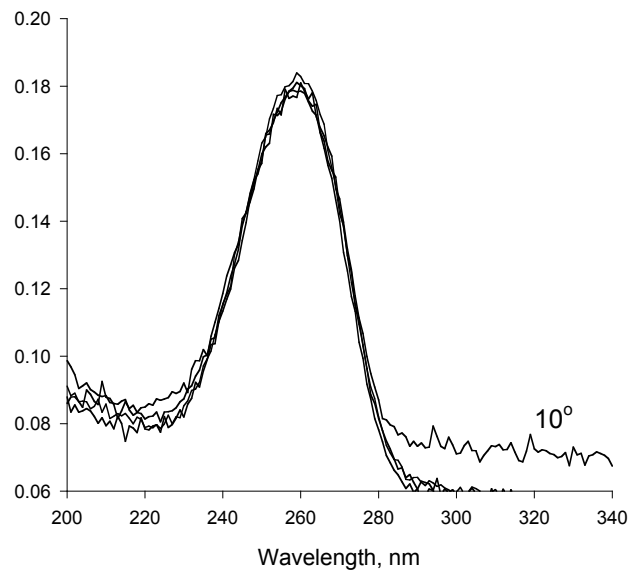
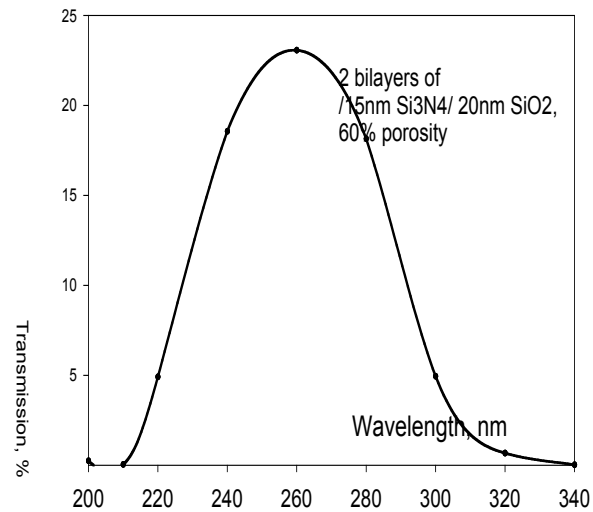
Near field transmission efficiency exceeds 50% within the pass band



Far field transmission efficiency exceeds 30% within the pass band



Optical testing of MPSi layer with multilayer coating



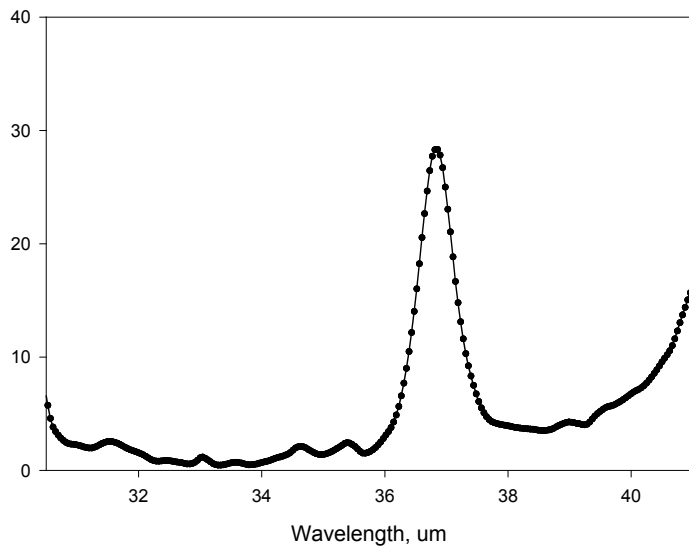
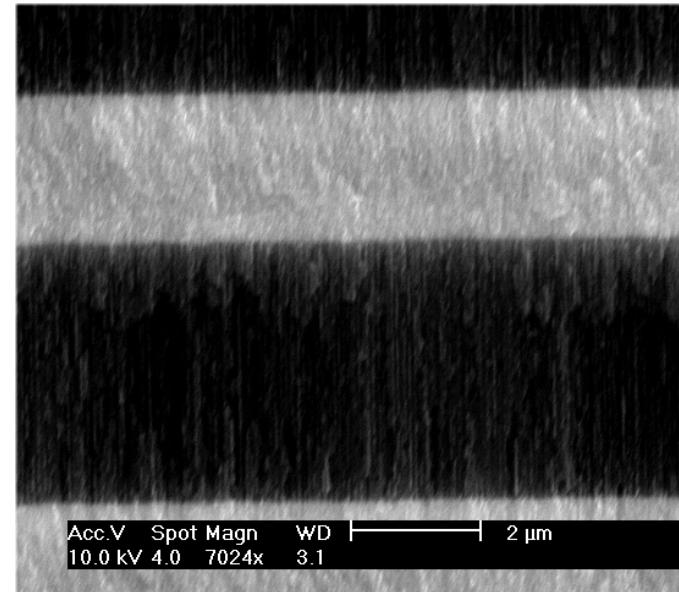
LakeShore.

Conclusions

- Pore formation process meet the requirements.
- Feasibility of ALD pore wall coating is demonstrated for Al_2O_3 single layer and a $\text{Al}_2\text{O}_3/\text{TiO}_2$ nanolaminated stack. Attempts at HfO_2 deposition have failed so far. No functional filter fabricated.
- Good agreement between theory and experiment. Good understanding of what's happening and what needs to be done.
- For further progress, an ALD machine at Lake Shore is required .

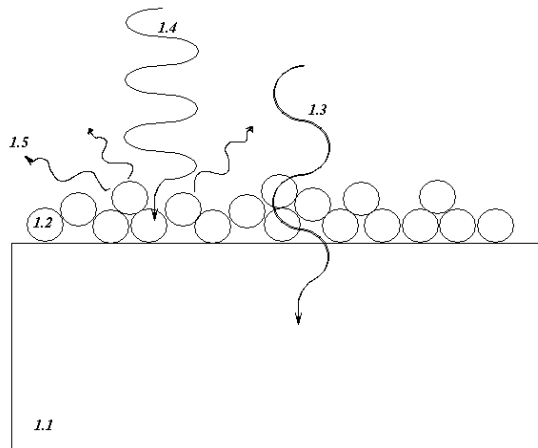
IR porous mesoporous silicon filters and mirrors

Consist of a porous silicon multilayer composed of alternated high-porosity/low porosity layers.

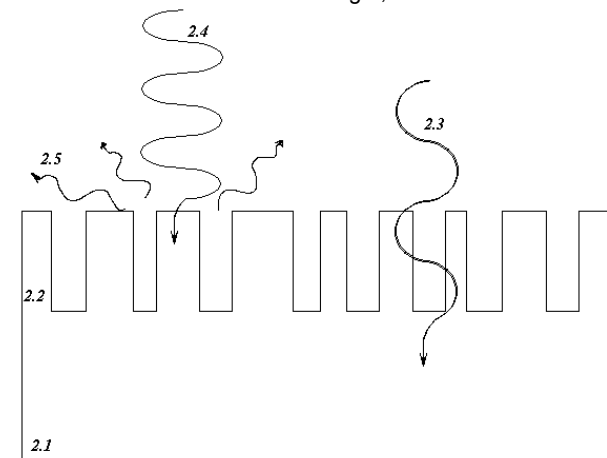
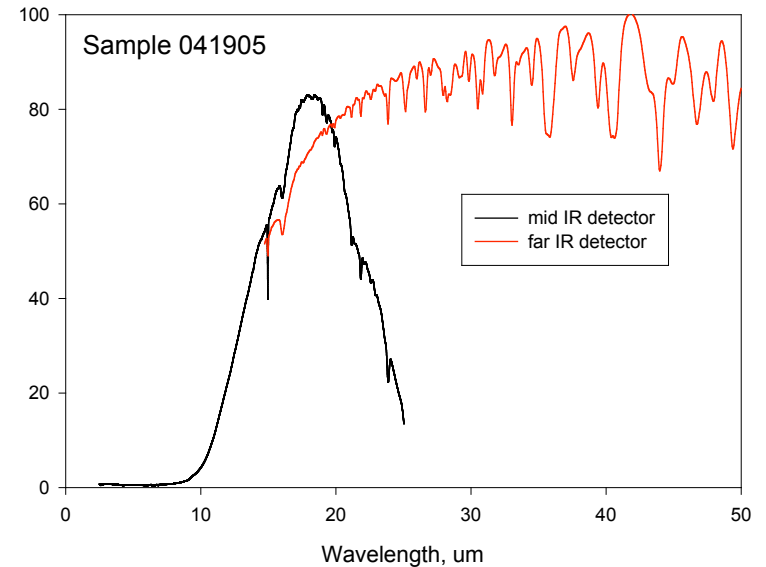


IR long wave pass filters

- Random MPSi layers
- Light scattering is the key
- Used as a part of almost any band-pass filter



Scattering by applied particles



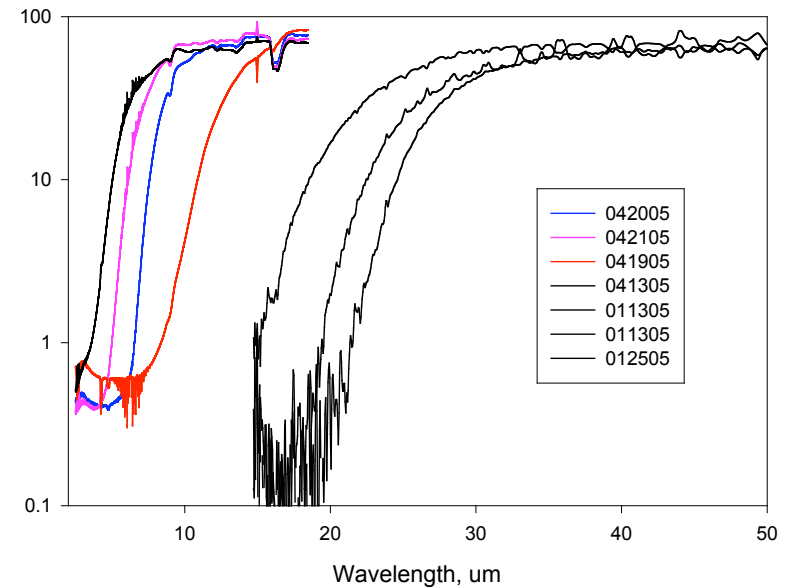
Scattering by random pores

LakeShore.

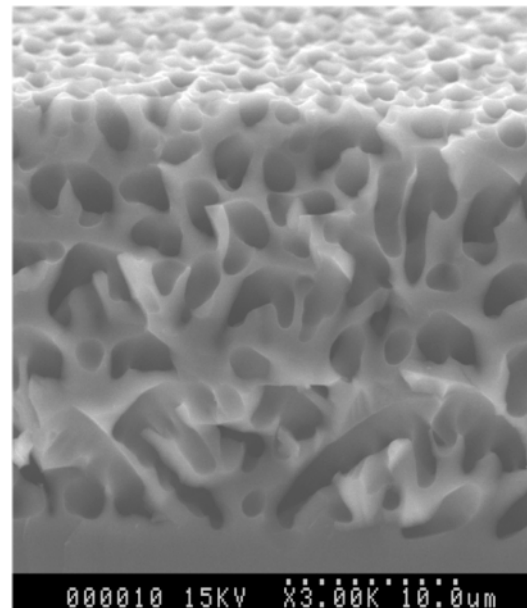
IR long wave pass filters (continuation)



Glancing angle reflection, 100mm wafer



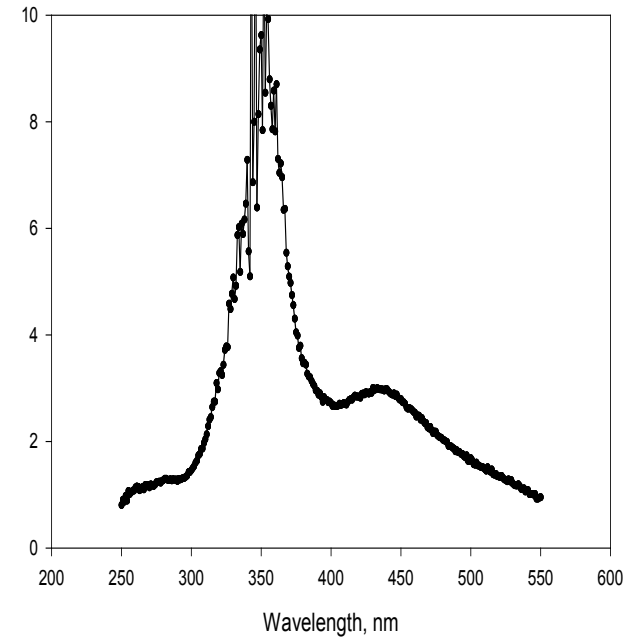
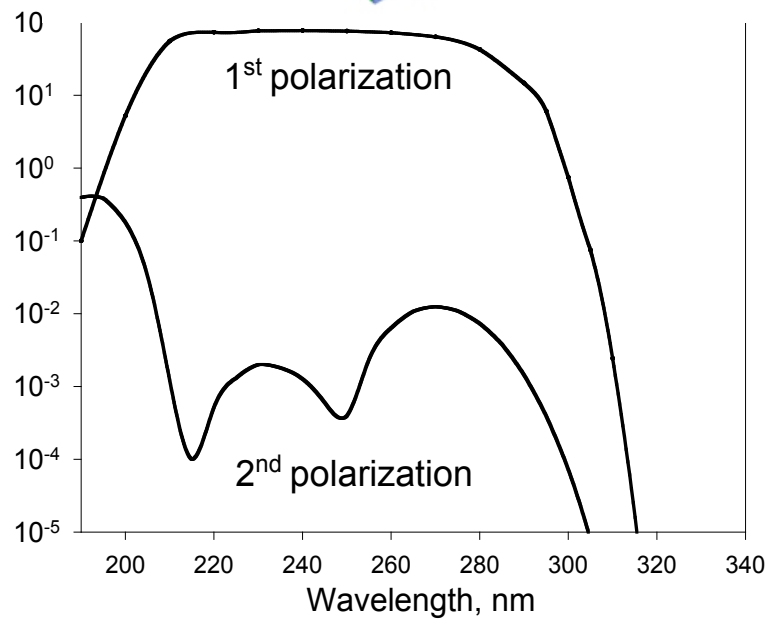
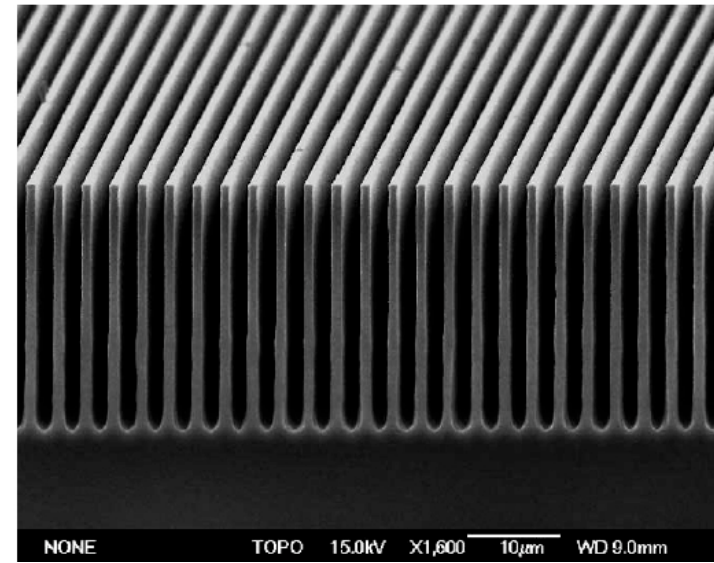
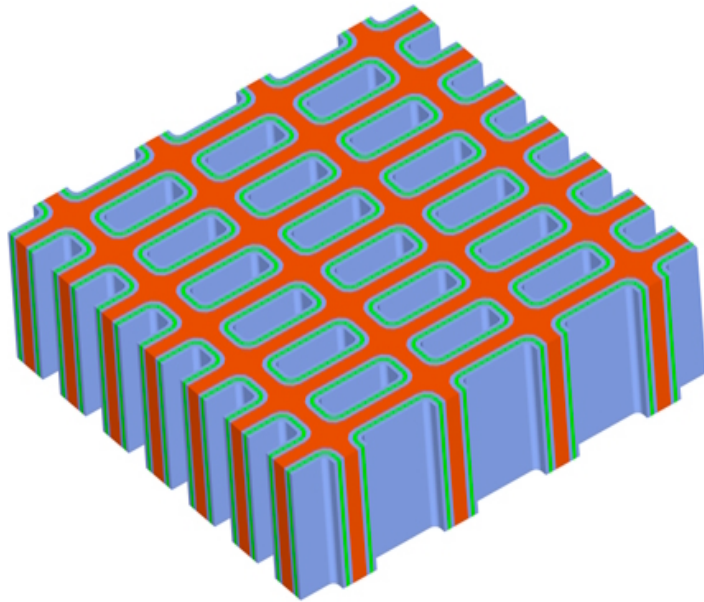
Normal to wafer surface



Pore layer cross section

LakeShore.

UV polarization components



LakeShore.